

Transaction Information

Tool ID	LATK762
Tool Status	Running Wafers
Location	Woodlands, Singapore
Wafer Size	300 mm
Fab Section	Lithography
Tool Available Date	2024-05-06

General Product Information

Vendor Supplier	TOKYO ELECTRON LIMITED
Model	LITHIUS I+
Vintage	2008
Serial No	G481358
Asset Description	TEL LITHIUS I+ ARF IMMERSION TRACK
Software Version	300.0.71.3
CIM	SECS
Process	ARF IMMERSION

Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Main System	PIR	2	OK
Main System	CPHP	16	OK
Main System	Main Tool	1	OK
Main System	ITC	3	OK
Main System	BCT	2	OK
Main System	EPHP	7	OK
Handler System	IRAI	1	OK
Handler System	IRAM	1	OK
Handler System	MPA	1	OK
Options System			

Hardware Configuration (Subfab / Auxilliary Units)

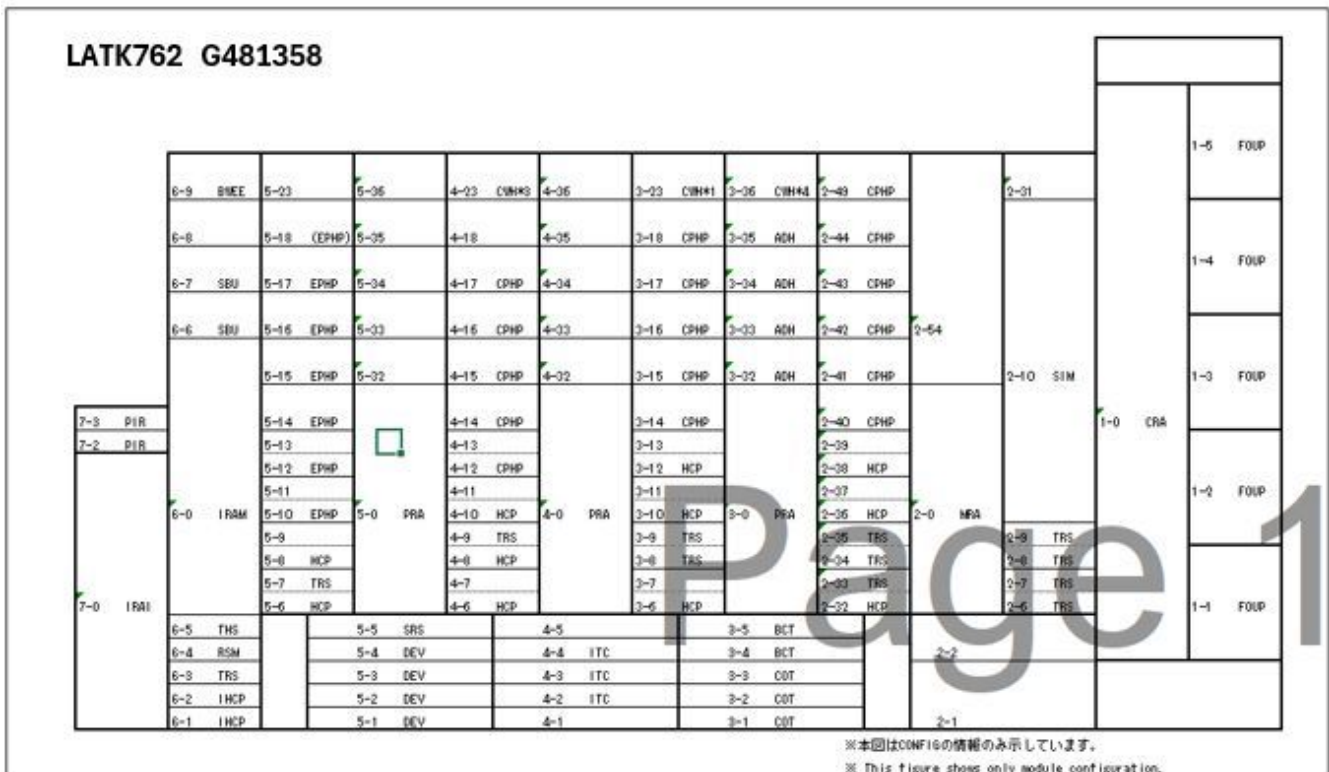
Description	Quantity	Status
AC Power Box	1	OK
DEV Chemical Cabinet	1	OK
T&H Controller	2	OK
COT Chemical Cabinet	1	OK

Missing/Faulty Parts / Accesories List

Description	Quantity
None	

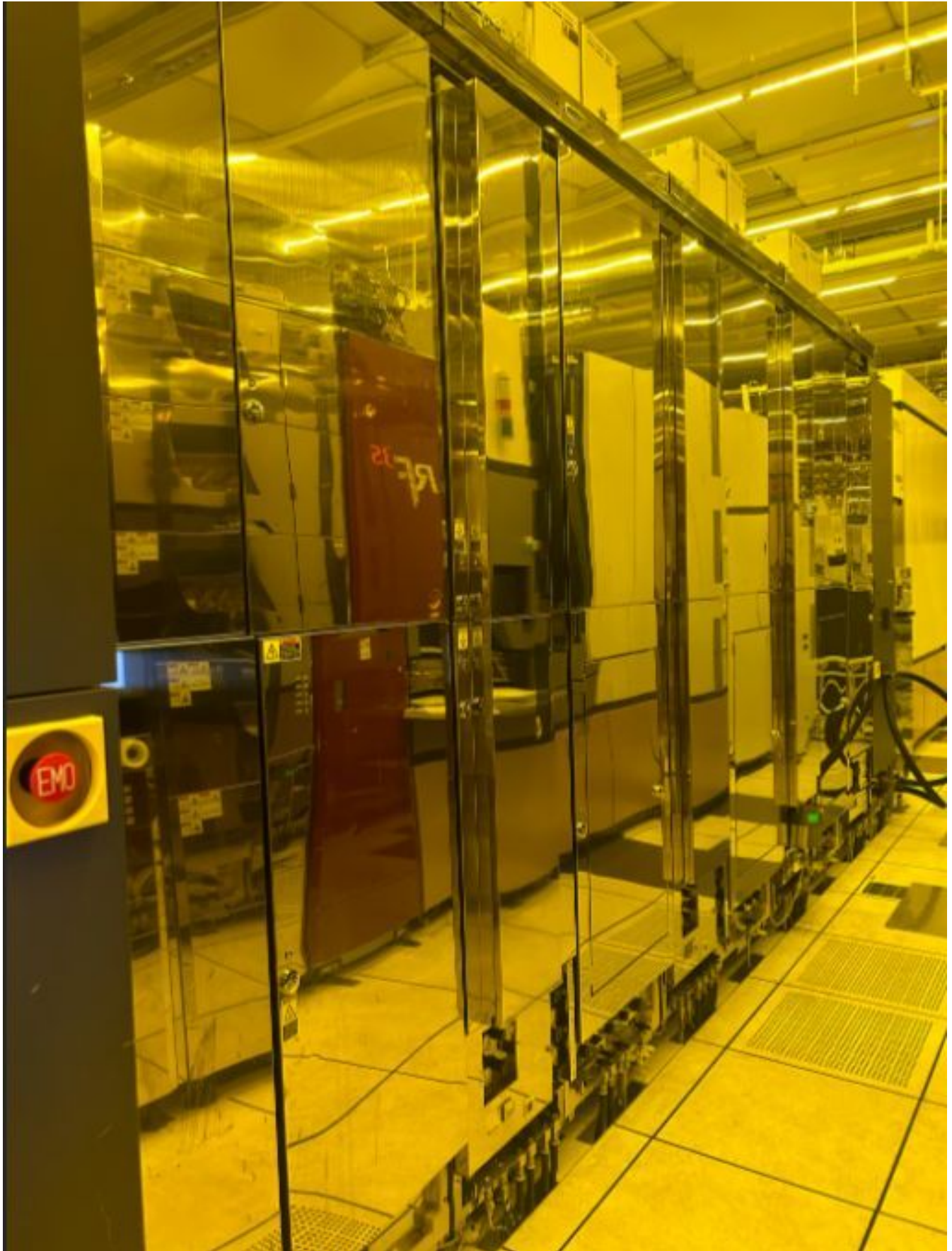
Tool Pictures

General	Tool Configuration
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Hardware Sub-fab

Hardware Config (Sub-Fab)









Manufacture Serial

Machine Serial Number

CLEAN TRACK



TOKYO ELECTRON KYUSHU LIMITED

MACHINE NO. G481358 DATE 08/08

ADDRESS: 1-1 FUKUHARA KOSHI-SHI
KUMAMOTO 861-1116. JAPAN

Made in Japan

Additional Configuration Files

Additional Configuration File

	Machine ID	G481358
	Software	300.0.71.3
	Tool Model	TEL LITHIUS i+
	Block	4 Block
CSB	Loadport	5
PRB1	CPHP	6
	HCP	3
	TRS	7
PRB2	ADH	4
	BCT	2
	COT	3
	CPHP	5
	HCP	3
	TRS	2
PRB3	ITC	3
	CPHP	5
	HCP	3
	TRS	1
PRB4	DEV	4
	SRS	1
	EPHP	7
	HCP	2
	TRS	1
IFB	BWEE	1
	IHCP	2
	PIR	2
	SBU	2
	TRS	1
Others	Pump Type	Entegris RGEN-02 4cc Entegris RGEN-02 10cc IGMINIPU2 Intelligen Mini 10cc
	Dev Nozzle Type	GP Nozzle MGP Nozzle
Accessories	AC Power Box	1
	T&H Controller	Shinwa ME1 Shinwa ME2
	Chemical Cabinet	2